

High-resolution imaging and high performance analysis by

Semi-in-lens objective lens.

The topmost surface imaging at

low accelerating voltage by

Gentle Beam mode (GB).

The Gentle Beam (GB) mode applies a negative voltage to a specimen and decelerates

incident electrons just before they irradiate the specimen, thus the

resolution is improved at an

extremely low accelerating voltage.

Therefore, 7610F is possible to

observe a topmost surface by a few

hundred eV, which were difficult to

observe conventionally, and

nonconductive samples such as

ceramics and semiconductor.



Is an ultra-high resolution Schottky Field Emission Scanning Electron Microscope which has semi-in-lens objective lens. High power optics can provide high throughput and high performance analysis. It is also suitable for high spatial resolution analysis. Furthermore, Gentle Beam mode can reduce the incident electron penetration to the specimen, enabling you to observe its topmost surface by using a few hundred landing energy.

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Scanning Electron Microscope

Ground Floor

Lab No.35

Building 13

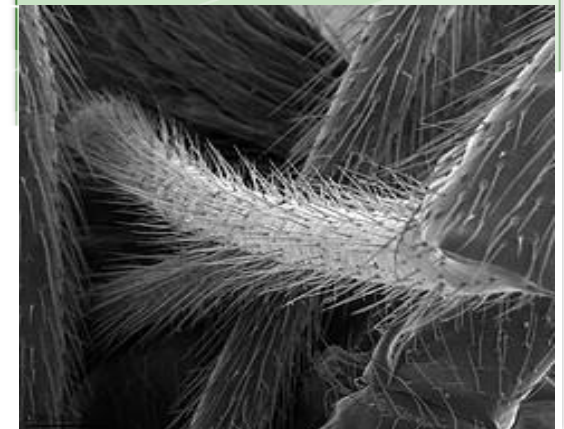
Central Laboratory
And
Prince Naif
Health Research Center

Medical Studies and
Scientific Sections

Scanning

Electron Microscope Unit

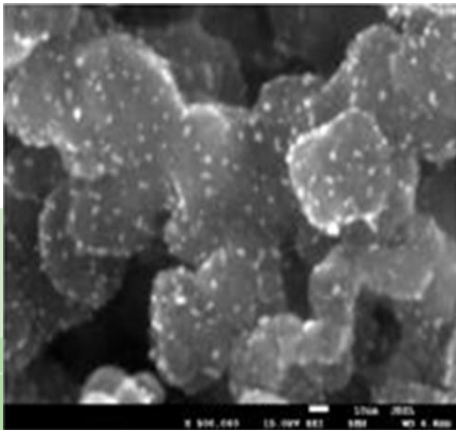
Field Emission



High throughput and high performance analysis by High Power Optics

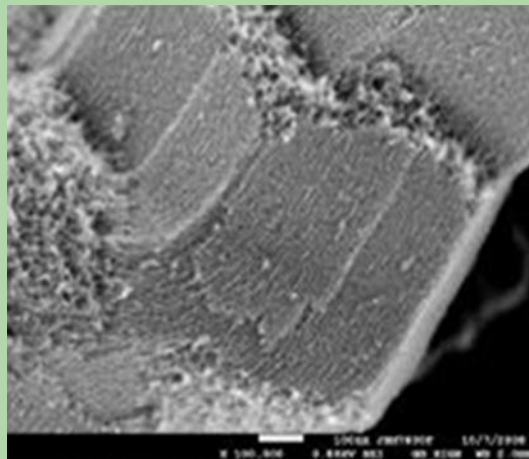
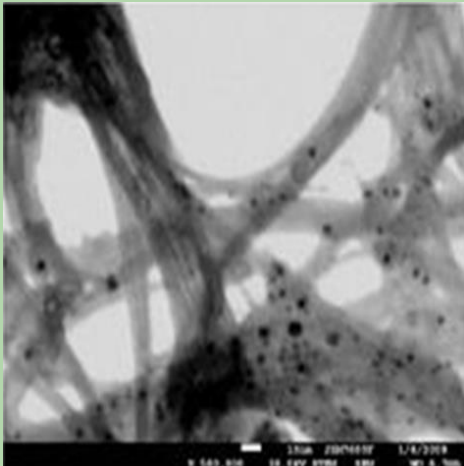
The High Power Optics produces fine electron probe for both observation and analysis.
The aperture angle control lens maintains a small probe diameter even at a larger probe current.
Using both techniques, the 7610F is suitable for a wide variety of analysis with EDS, WDS, CL.

Sample: Pt Catalyst Accelerating
Voltage 15 kV

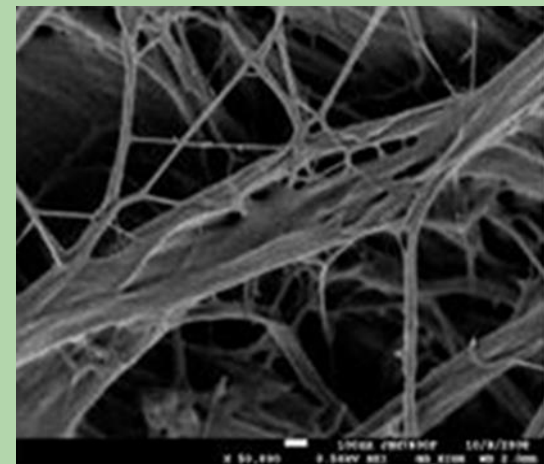


The topmost surface imaging at ultra-low landing energy by
Gentle Beam mode (GB)

Sample: Carbon Nanotubes
Accelerating Voltage 30 KV



Sample: Mesoporous Silica landing
energy 800 eV



Sample: filter Landing energy 500 eV